		The state of the s	- Conta					
Form PTO 1449		U.S. DEPARTMENT OF COMMERCE		ATTY DOCKET NO.		SERIAL NO.		
(Modified) PATENT AND TRADEMAR			EMARK OFFICE	236518US41YA		10/673,138		
			APPLICANT					
LIST OF	REFE	RENCES CITED BY API	PLICANT	Eric J STRANG, et al.				
				FILING DATE		GROUP		
				September 30, 2003		2128		
U.S. PATENT DOCUMENTS								
EXAMINER		DOCUMENT	NAME I NAME I NAME					
INITIAL		NUMBER				CLASS	CLASS IF APPROPRIATE	
	AA		3/14/2002	Ozaki				
	AB	US 5,719,796	2/17/1998	CHEN				
	AC							
	AD							
	AE							
	AK				-			
	AF		,					
	AG							
	AH							
FOREIGN PATENT DOCUMENTS								
		DOCUMENT NUMBER	DATE	COUNTRY		TRANS YES		SLATION NO
	Al	CN 1335558A	2/13/2002	China (with Partial English Translation))	China (with Partial English Translation))			
	AJ	JP 11-176906	7/2/1999	JAPAN (with English Abstract)				Х
	AK	KR 1999-071784	4/2/1999	Korea (with corresponding to US. Pater Application No. 5,719,796 attached as a herewith)	on No. 5,719,796 attached as a courtesy			
	AL						L	
	Including Author, Title, Date, Pertinent	t Pages, etc.)						
Agam SHAH, "TILERA TARGETS INTEL, AMD WITH 100-CORE PROCESSOR", PCWorld Solved, IDG News October 26,								
	AL	2009, pages 1-3						
	АМ	Robert W. ATHERTON, et al., "DETAILED SIMULATION FOR SEMICONDUCTOR MANUFACTURING", Proceedings of the 1990 Winter Simulation Conference, ppgs 659-663						
	221	Angus J. MACDONALD, et al. "INTEGRATING CAM AND PROCESS SIMULATION TO ENHANCE ON-LINE ANALYSIS						
	AN	AND CONTROL OF IC FABRICATION", IEEE Transactions On Semiconductor Conductor Manufacturing, Vol., 3. No. 2, May 1990, pages 72-79						
	AO	Yea-Huey Su, et al, "A CONCEPTUAL FRAMEWORK FOR MANUFACTURNG SERVICE PROVISIONING BY VIRTUAL FABS", 1998 Semiconductor Manufacturing Technology Workshop, pages 75-85						
		Chanettre RASMIDATTA, et al. "NEW APPROACHES FOR SIMULATION OF WAFER FABRICATION: THE USE OF						
	AP	CONTROL VARIATES AND CALIBRATION METRICS", Proceedings of the 2002 Winter Simulation Conference, pages 1414-1422						
	AQ	Office Action issued March 30, 2011 in Japanese Patent Application No. 10-2006-7006632, (with English-language Translation) pages 1-17						
	AR	Naomi YONEMURA, et al. "HEAT ANALYSIS ON INSULATED METAL SUBSTRATES", Proc. Of the 1994 IMC, 110 (1994), pages 1407-1410						
	AS	Tony C. MIDEA, "1999 CASTING SIMULATION SOFTWARD SURVEY", AFS Process Design and Modeling Committee (1-						
AS F), Ďavid Schmidt, Finite Solutions, Inc., Arlington Heights, ILL pages 1-4								
	AT				Additional References sheet(s) attached			
Examiner					Date Considered			
*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								